

**ABSTRACT:**

Method of manufacturing a thin-film magnetic head, and magnetic head manufactured by means of said method.

Method of manufacturing a thin-film magnetic head provided with a transducing element (23) and at least one flux-guiding element (17a, 17b). An electrically conducting layer (8) of a non-magnetic material and a second electrically insulating layer (9) of a non-magnetic material are successively formed on a first  
5 electrically insulating layer (5) of a non-magnetic material. The second electrically insulating layer is subsequently provided with at least an interruption exposing a portion of the electrically conducting layer. Subsequently, the flux-guiding element is formed by electrodepositing a soft-magnetic material on said portion until the interruption is filled, whereby the flux-guiding element and the second electrically insulating layer constitute  
10 an at least substantially plane surface on which an electrically insulating spacer layer (21) is formed. Subsequently, the transducing element is provided on the spacer layer. The magnetic head thus formed has a non-magnetic transducing gap (35) terminating in a head face (33) and being constituted by the first electrically insulating layer (5) and the electrically conducting layer (8).

(Fig. 15)

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